IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

S. KONDO, et al.

Application No.:

Rule 53(b) of No. 10/441,063

Filed:

April 16, 2004

For:

POLISHING METHOD

Expected

Group:

2812

Expected

Examiner:

B. Tran

<u>INFORMATION DISCLOSURE STATEMENT</u> <u>UNDER 37 CFR § 1.97 AND § 1.98</u>

Mail Stop Patent Application Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 April 16, 2004

Sir:

Pursuant to Applicants' duty of disclosure, enclosed please find a List, on a form substantially equivalent to Form PTO-1449, of documents cited in connection with at least one of (a) prior Application No. 09/182,438, filed October 30, 1998, (b) a Re-examination proceeding concerning the patent issuing from No. 09/182,438, (c) prior Application No. 09/618,999, filed July 18, 2000, and (d) prior Application No. 10/441,063, filed May 20, 2003.

Since prior Application No. 09/182,438, No. 09/618,999 and No. 10/441,063 are being relied upon in the above-identified application under 35 USC §120, copies of the listed documents are not enclosed. See 37 CFR § 1.98(d).

501.36636CC3

This Information Disclosure Statement is being submitted concurrently with the filing of the above-identified Continuation application. Accordingly, requirements of 37 CFR §1.97(b) are satisfied.

In view of all of the foregoing, it is respectfully submitted that all applicable requirements of 37 CFR §1.97 and §1.98 have been satisfied, in connection with all documents on the enclosed List. Accordingly, consideration of the listed documents, upon examination of the above-identified application, is respectfully requested.

Please charge any shortage in the fees due in connection with the filing of this paper, including extension of time fees and excess claim fees, to Deposit Account No. 01-2135 (referencing case No. 501.36636CC3), and please credit any excess fees to such deposit account.

Respectfully submitted,

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WIS/sjg

Form PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DKT. NO. 501.36636CC3	SERIAL NO. TBD		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		APPLICANT KONDO, et al.			
(U	se several sheets if necessary)	FILING DATE April 16, 2004	GROUP 2812		

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class 438	Subclass 693	Filing Date
AA	5,858,813	1-12-99	1-12-99 Scherber, et al.			
AB	5,866,031	2-2-99	Carpio, et al.	252	79.1	
AC	5,840,629	11-24-98	Carpio	438	692	
AD	5,783,489	7-21-98	Kaufman, et al.	438	692	
AE	5,759,917	6-2-98	Grover	438	690	
AF	5,733,176	3-31-98	Robinson, et al.	451	41	<u> </u>
AG	5,695,660	12-9-97	Litvak	216	85	<u> </u>
AH	5,676,760	10-14-97	Aoki, et al.	134	1.3	
AI	4,944,836	6-90	Beyer, et al.			
AJ					 	
AK					 	
AL					 	

FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation	
			Country	Class		Yes	No
AM		T		· · · · · · · · · · · · · · · · · · ·	+	 	
AN					 		
AO							
AP						 	
AQ		1.				 	
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AS					 	 	
AT					 	<u></u>	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	OWIEN 15 (Including Author, 1 life, Date, Pertinent Pages, Etc.)				
AU	"Pattern Geometry Effects in the Chemical-Mechanical Polishing of Inlaid Copper Structures", J. Electrochem. Soc., vol. 141, p. 2842-2848, October 10, 1994.				
AV	"An Examination of Slurry for Wiring Metal's Chemical-Mechanical Polishing", vol. 41, p. 35-37, June 1997 (in Japanese)				
AW	"Semiconductor International", Semiconductor World, p. 171-172, May 1995 (in Japanese)				
AX	"Electrochemical Potential Measurements during the Chemical-Mechanical Polishing of Copper Thin Films", J.E. Electrochem. Soc., vol. 142, July 7, 1995 p. 2379-2385				
AY	"Chemical Mechanical Polishing of Copper using a Slurry composed of glycine and hydrogen peroxide", CMP-MIC Conferences 1996 ISMIC, February 22-23, 1996, CMP p. 119-123.				
	Kashiwagi, The Science of CMP (1997), p. 299-300.				
Examiner	Date Considered				

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FORM PTO-1449 U.S. Department of Commerce (Rev. 4/92) Patent and Trademark Office INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)			ATTY. DOCKET NO. 501.36636003		SERIAL NO.		
			APPLICANT KONDO, et al.				
			FILING DATE April 16, 2004	GROUP 2812			
		U.S. PATENT	DOCUMENTS				
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
	5,770,095	06/1998	Sasaki, et al				

U.S. PATEN EXAMINER INITIAL DOCUMENT NUMBER DATE 5,770,095 06/1998 6,117,783 09/2000 Small, et al. 6,001,269 12/1999 Suthuraman, et al. 5,932,486 08/1999 Cook, et al. 5,875,507 03/1999 Stephens 5,972,792 10/1999 Hudson 5,575,885 1996 Hirabayashi, et al. **FOREIGN PATENT DOCUMENTS** Translation/ ABSTRACT DOCUMENT NUMBER DATE COUNTRY CLASS SUBCLASS YES NO 07-233485 1995 Japan Х 1995 07-161669 Japan X OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.) **EXAMINER DATE CONSIDERED**

EXAMINER: Initial if citation is considered, draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

(Form PTO-1449 [6-4])